



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Pablo I. Rovira; ;
Assignee: Nanometrics Incorporated
Title: Optical Metrology System with Combined Interferometer and Ellipsometer
Serial No.: 10/016,943 Filing Date: December 13, 2001
Examiner: Samual A. Turner Group Art Unit: 2877
Docket No.: NAN051 US Confirmation No.: 7400

Santa Clara, California
May 5, 2004

Mail Stop Issue Fee
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR §1.97(i)**

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, §1.97(i) and §1.98, the Applicants submit in the above-identified patent examination the document listed on the accompanying Form PTO-1449. A copy of the documents is also submitted herewith. Applicants request that this document is placed in the file.

This Information Disclosure Statement is submitted pursuant to 37 CFR §1.97(i). Accordingly, a fee is not required.

The information contained in this Information Disclosure Statement under 37 C.F.R. §1.555 is to the best of my knowledge and is not to be construed as a representation that: (i) a complete search has been made; (ii) additional information material to the examination of this application does not exist; (iii) the information, protocols, results and the like reported by third parties are accurate or enabling; or (iv) the above information constitutes prior art to the subject invention.

Via Express Mail Label No.
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Respectfully submitted,

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 <p>U.S. Department of Commerce, Patent and Trademark Office</p> <p>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</p> <p>(Use several sheets if necessary)</p>	Application No.:	10/016,943
	Filing Date:	December 13, 2001
	First Named Inventor:	Pablo I. Rovira
	Group Art Unit:	2877
	Examiner Name:	Samuel A. Turner
	Confirmation No.:	7400
	Attorney Docket No.:	NAN051 US

Examiner:	Date Considered:
* Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication with applicant.	